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Autore	Luzzatto-Fegiz, Pierpaolo
Titolo	La popolazione di Trieste (1875-1928) / Pierpaolo Luzzatto Fegiz
Pubbl/distr/stampa	Trieste : Officine Grafiche de la Editoriale Libreria, 1929
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Altri autori (Persone)	KimSeong H DuggerMichael T MittalK. L. <1945->
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Nota di contenuto	pt. 1. Understanding through continuum theory -- pt. 2. Computer simulation of interfaces -- pt. 3. Adhesion and friction measurements -- pt. 4. Adhesion in practical applications -- pt. 5. Adhesion mitigation strategies.
Sommario/riassunto	Phenomena associated with the adhesion interaction of surfaces have been a critical aspect of micro- and nanosystem development and performance since the first MicroElectroMechanicalSystems(MEMS) were fabricated. These phenomena are ubiquitous in nature and are present in all systems, however MEMS devices are particularly sensitive to their effects owing to their small size and limited actuation force that can be generated. Extension of MEMS technology concepts to the nanoscale and development of NanoElectroMechanicalSystems(NEMS) will result in systems even more strongly influenced by surface